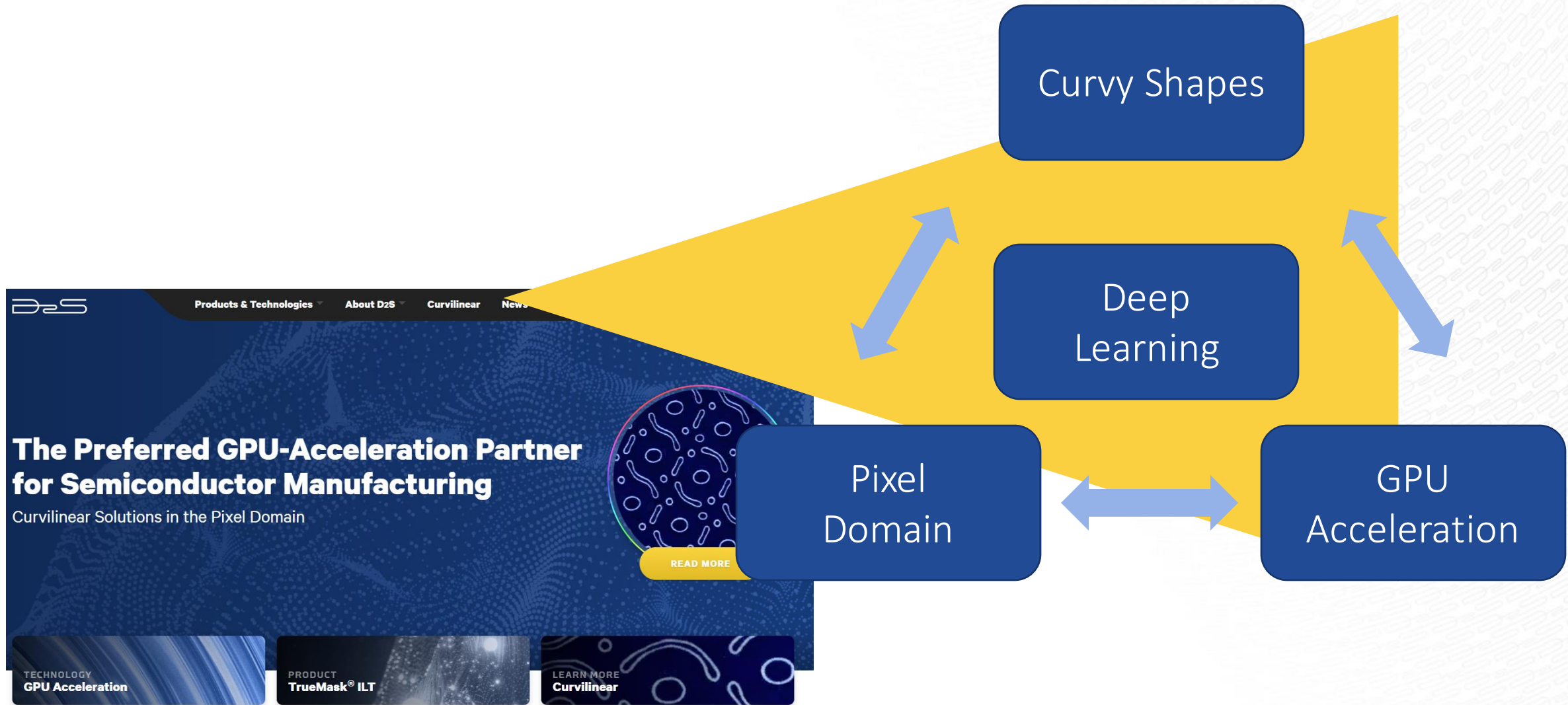




September 2022 | Aki Fujimura, CEO D2S, Inc.

# $O(p)$ : GPUs, Pixels, DL, Curvy Masks & Designs

# D2S Does GPU Acceleration



# GPU Accelerates Edge Manipulation, Too

**Manhattan OPC**

**Curvy ILT**

**Fracturing**

**MB-MDP (overlapping)**

**MWCO\***

**Piecewise Linear Polygons**

**Curves (Bezier/Spline)**

**Pixels**

**VSB**

**Multi-beam**

The graphic is split into two vertical panels. The left panel is grey and contains: 'Manhattan OPC' with a stepped edge diagram; 'Fracturing' with a diagram of a fractured edge; 'MB-MDP (overlapping)' with a diagram of overlapping mask blocks; and 'VSB' with a diagram of a variable space beam lithography system. The right panel is blue and contains: 'Curvy ILT' with a grayscale image of a circular pattern; 'MWCO\*' with a diagram of overlapping mask blocks; 'Piecewise Linear Polygons' with a diagram of a curve approximated by line segments; 'Curves (Bezier/Spline)' with a diagram of a smooth curve; 'Pixels' with a 3x3 grayscale grid; and 'Multi-beam' with a diagram of a multi-beam lithography system.



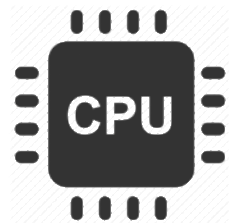
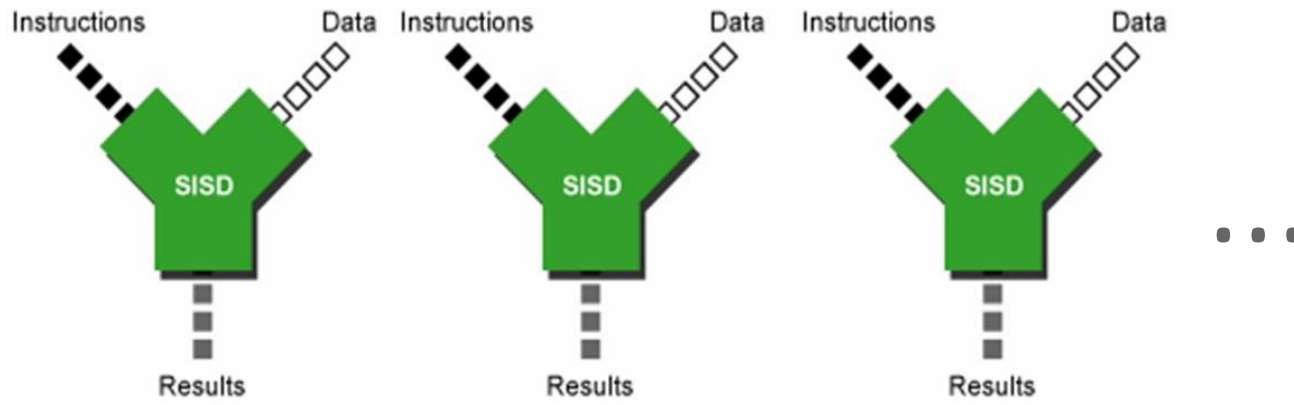
# GPU is Great for Curvy

$O(p)$

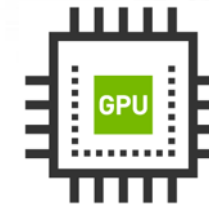
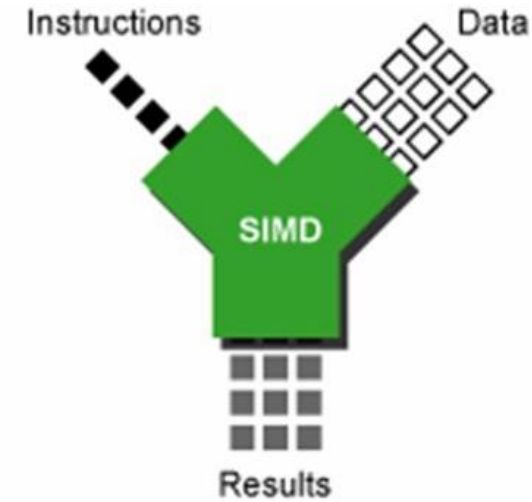
Because GPU is even better at pixels



# GPU is SIMD and SIMD is Great at Pixels



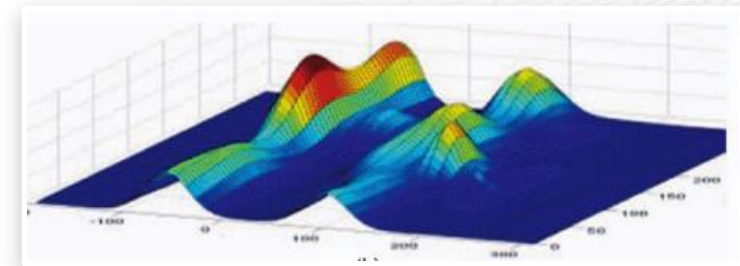
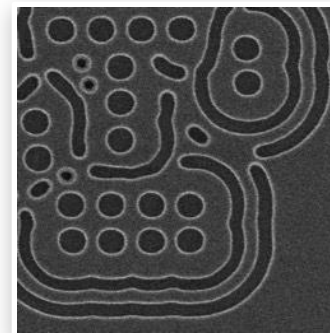
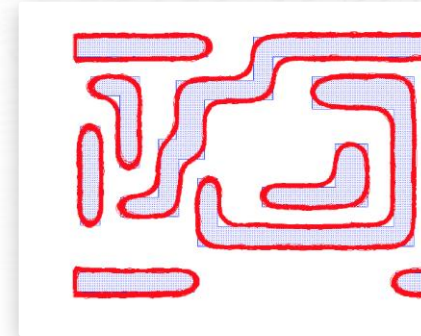
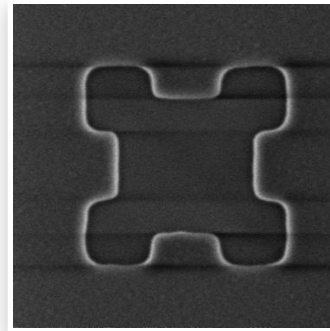
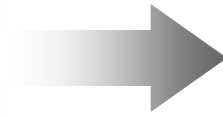
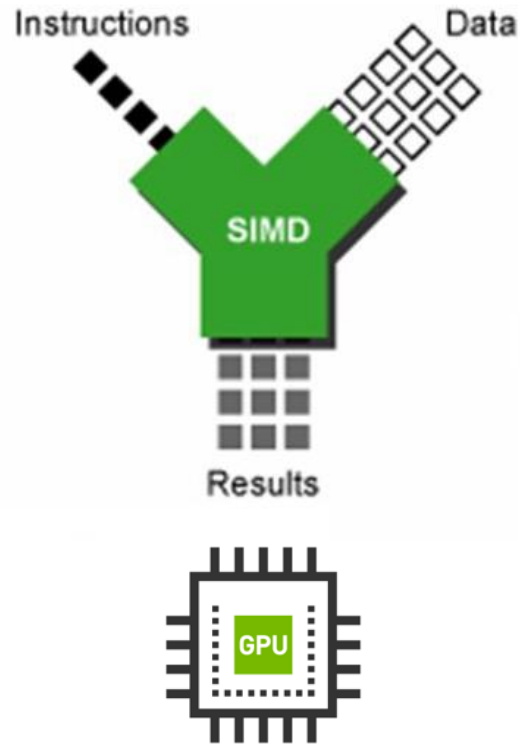
Multiple Single Instruction Single Data  
(SISD)



Single Instruction Multiple Data  
(SIMD)



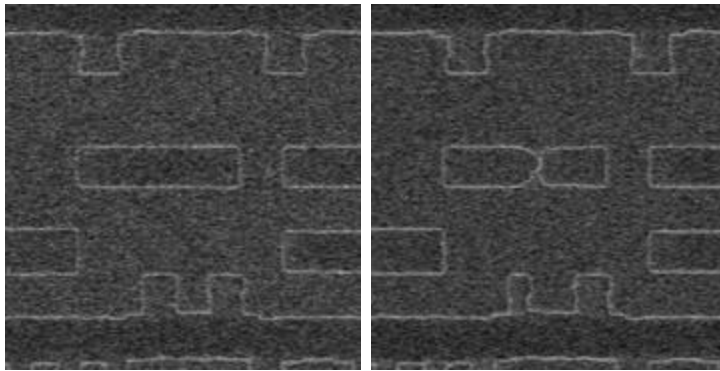
# Mask and Wafer Effects are SIMD



**Because nature is SIMD**

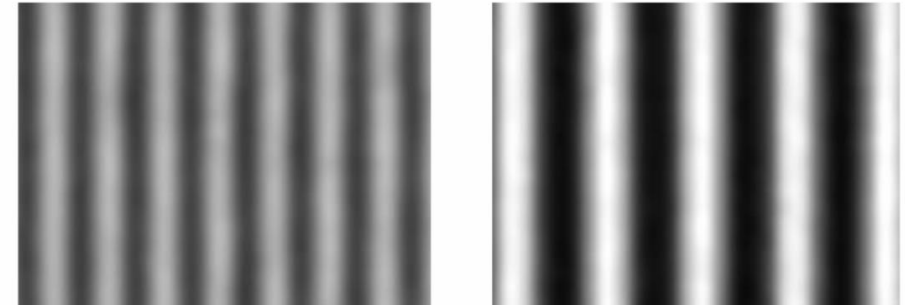


# Image Processing is SIMD, Too



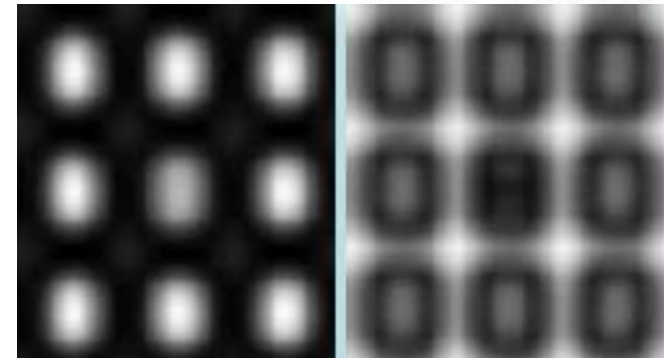
Source: NuFlare/CDLe

SEM



Source: Lasertec/BACUS Newsletter

Inspection



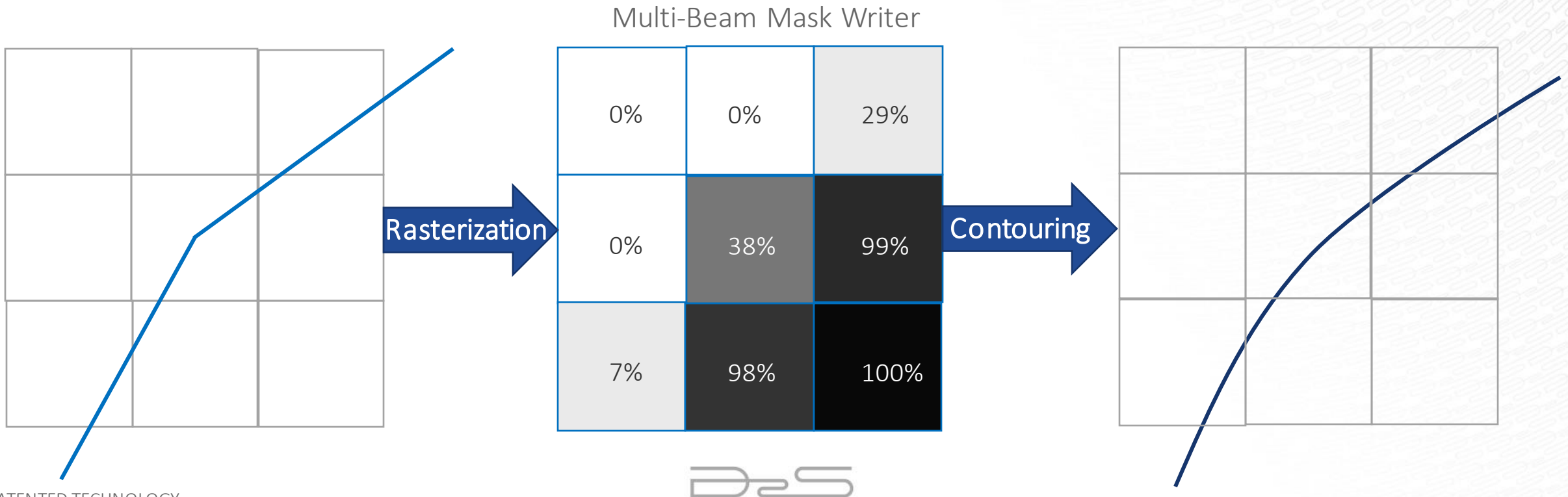
Source: L Pang, et al., "Expanding the applications of computational lithography and inspection (CLI) in mask inspection, metrology, review, and repair"

Because Images are Arrays of Pixels



# Pixel-Based and Edge-Based are Duals

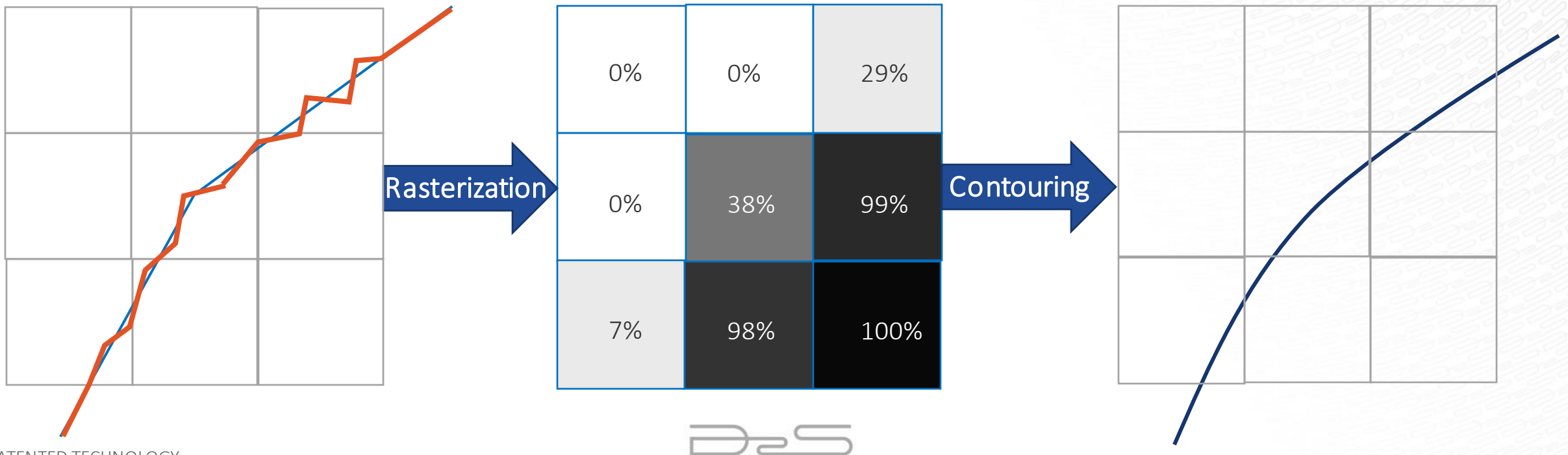
- Whatever you can do in one can be done in the other...given a resolution limit determined by “Nyquist”
- The only question is performance....





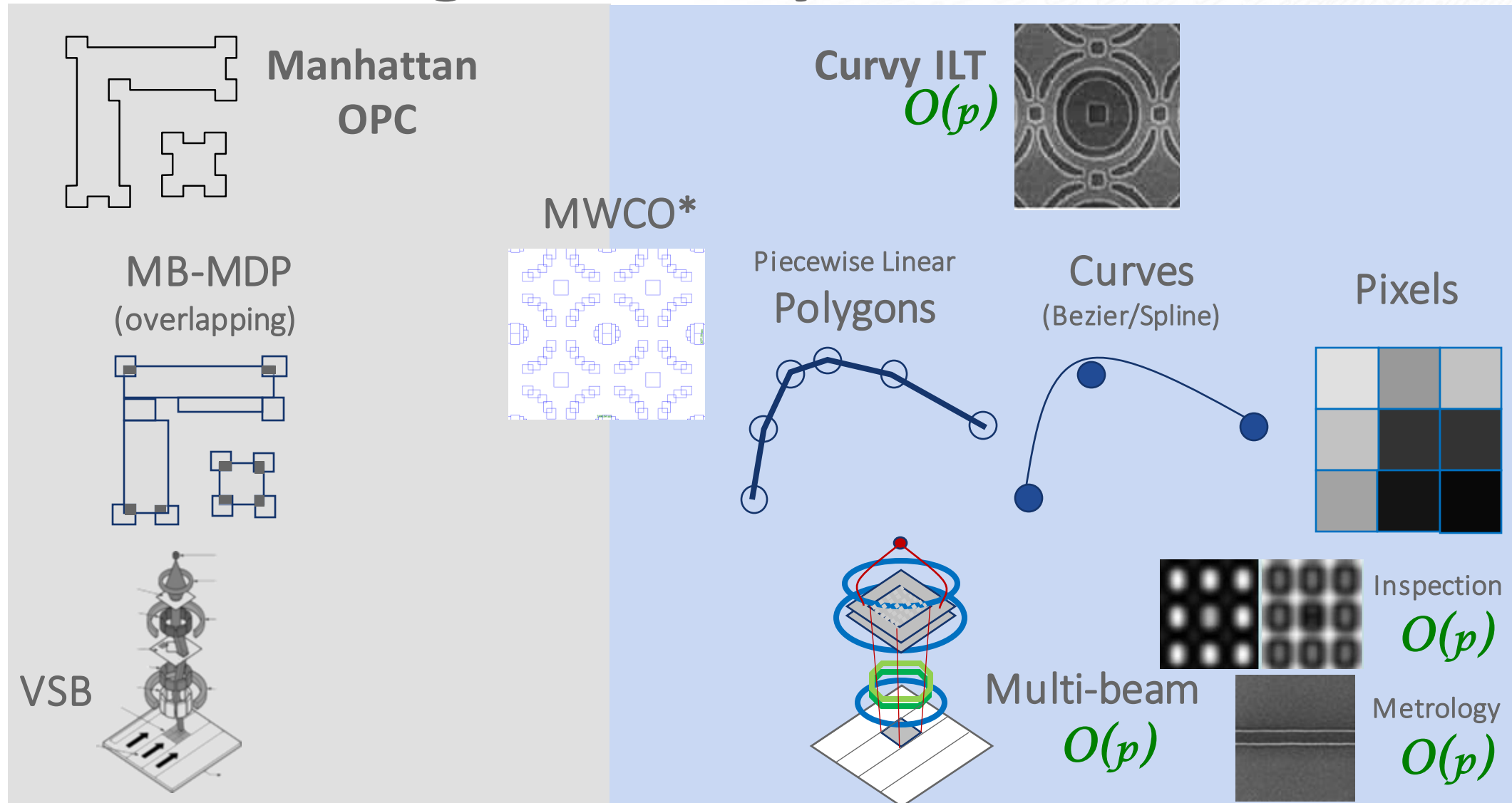
# This Also Rasterizes Exactly the Same

- Rasterization is inherently a low-pass filter
- Red and blue become the same in pixels, but red uses much more data
- Curvilinear format would also become the same in pixels and thereafter
  - And represents the actual contoured shape that would be on the physical mask

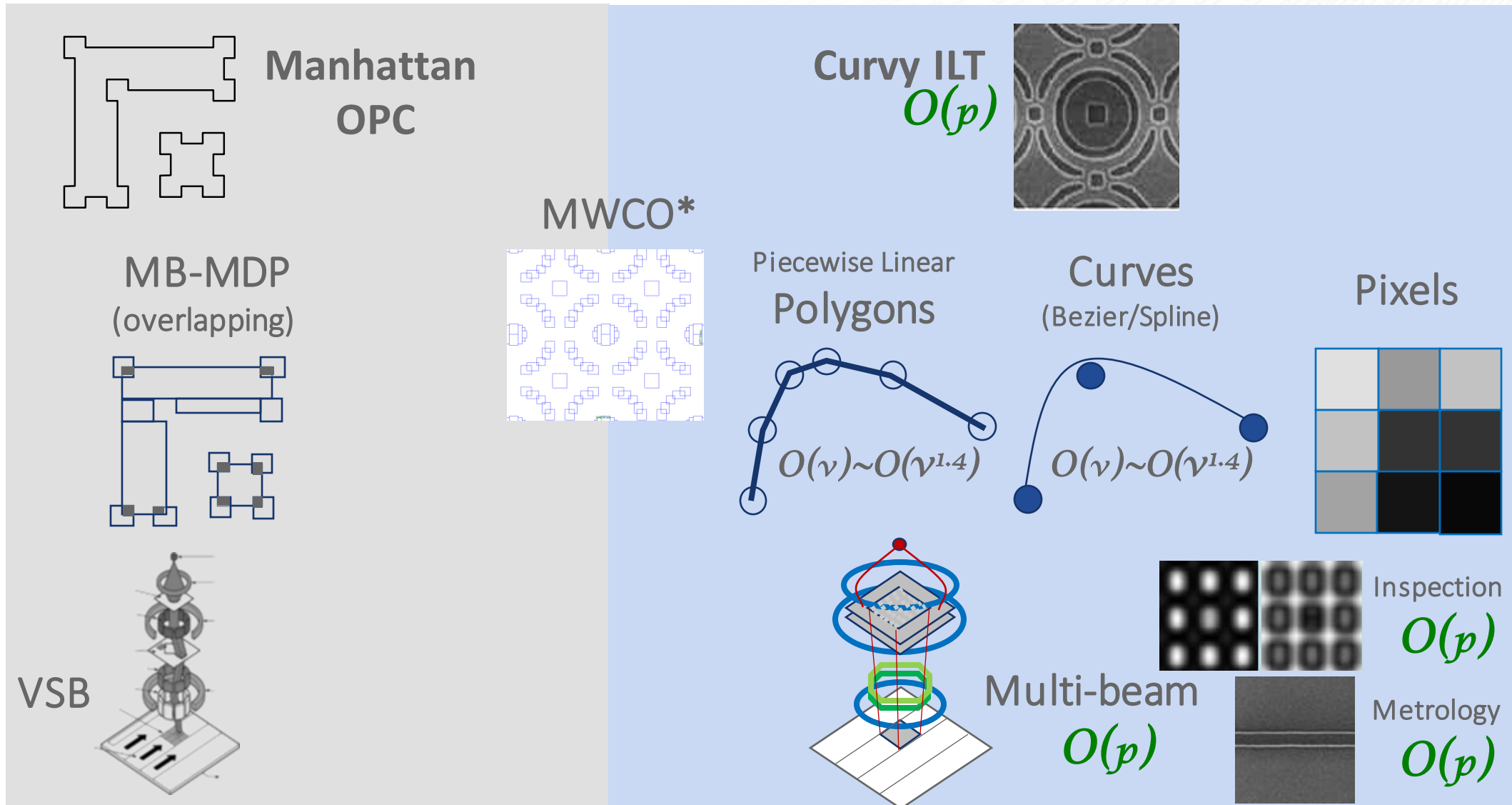


D<sub>2</sub>S

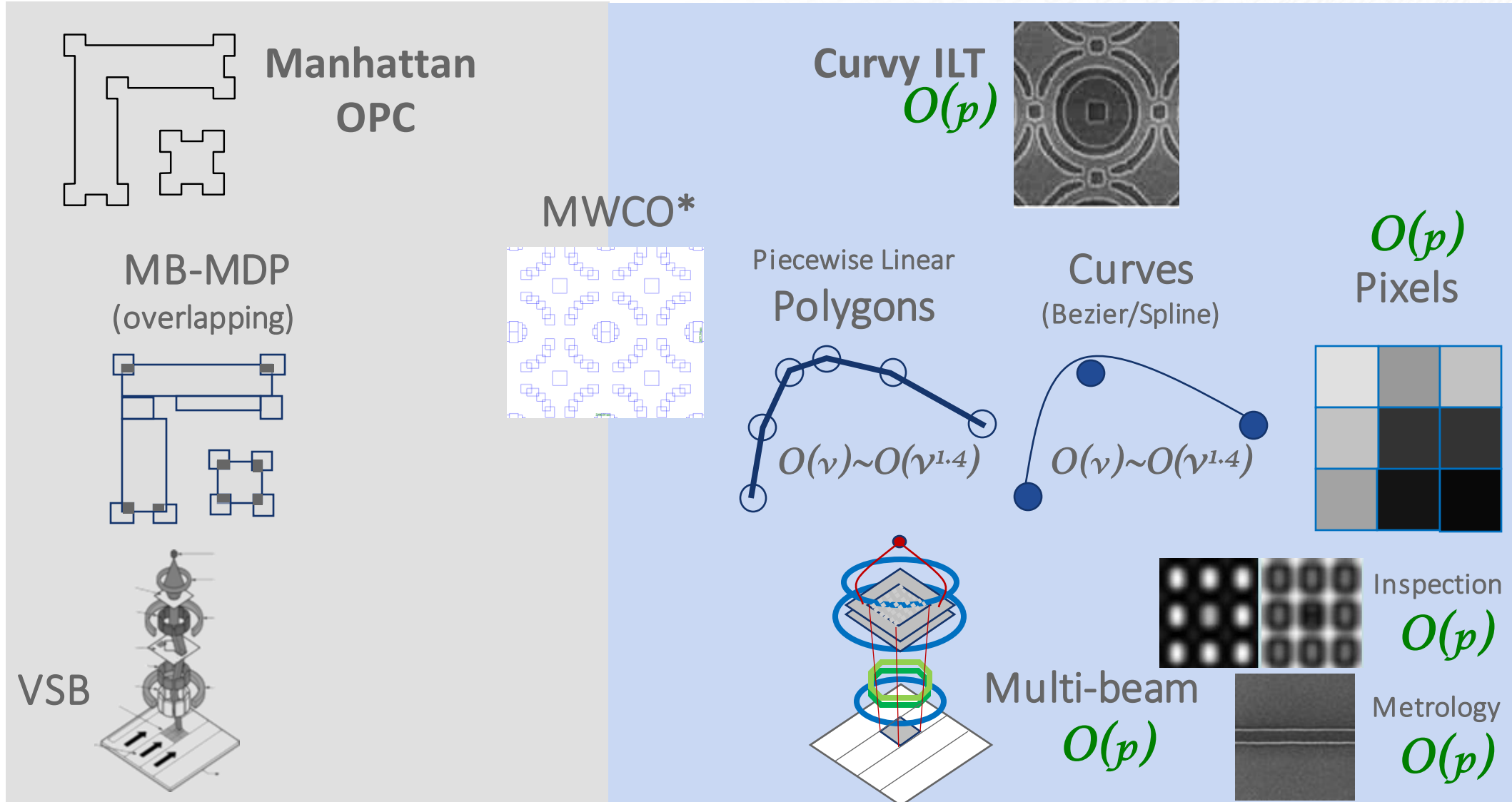
# Mask-Making is Already Pixel-Based



# Datapath is Not

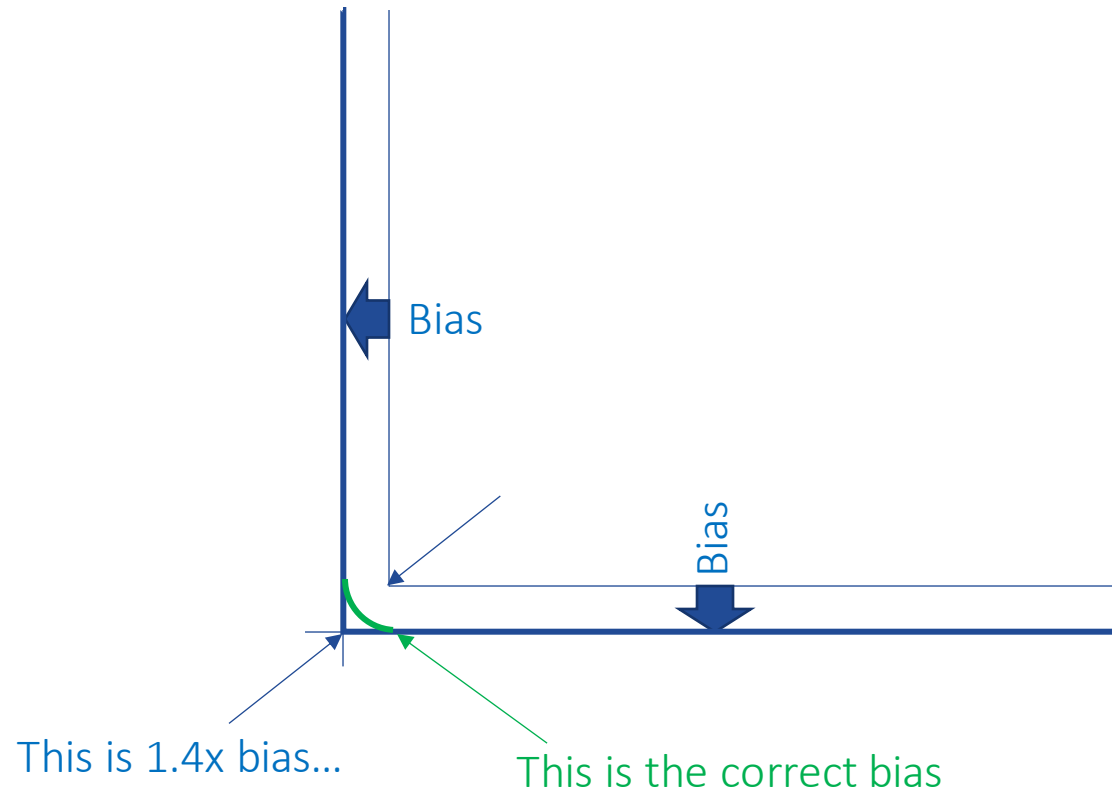


# D2S is Adding a Pixel-Based Datapath



# Edge or Pixel, Curvy Improves Manufacturing

## *Simple example : Biasing*



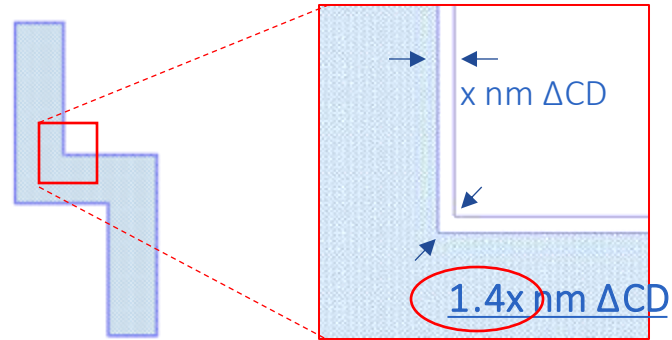
For traditional Manhattan edge-based CAD, it is bad to have bias create curvy shapes. So this is understandable but incorrect. Etching, for example, doesn't work that way.

# Even a Simple Bias Operation is Better with Curvy

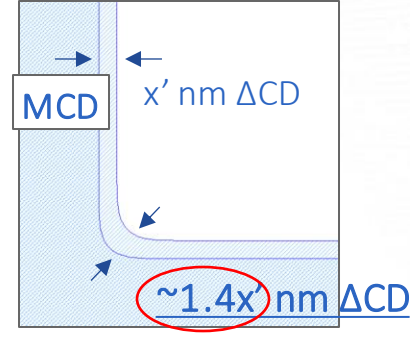
*Rectilinear bias is off by 40% on corners*

Rectilinear

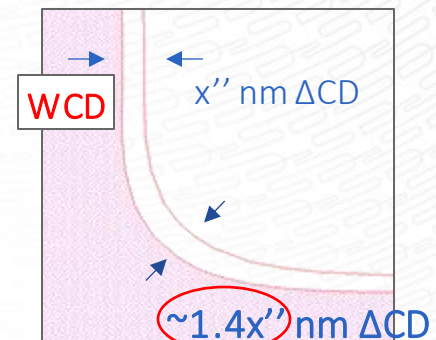
Mask Design



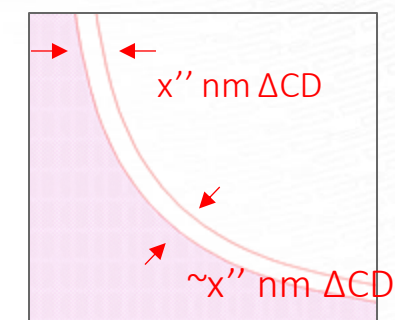
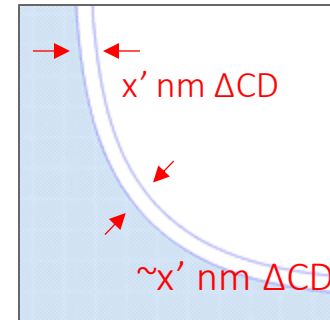
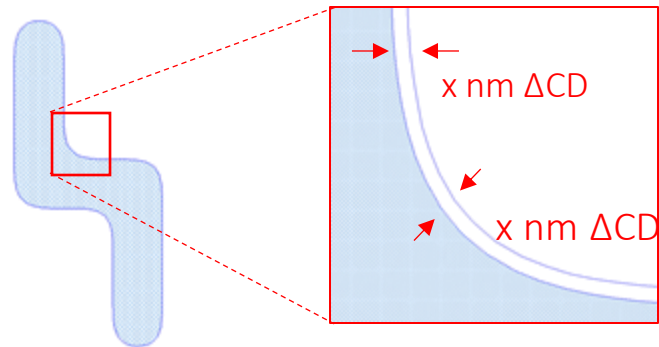
eBeam w/ bias



Litho sim. w/ bias



Curvilinear

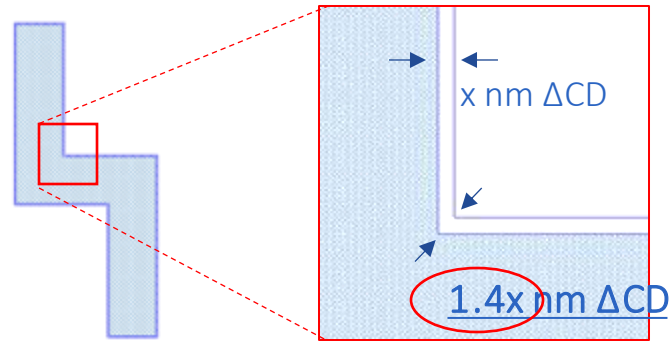


# Even Worse is Manufacturing Variation

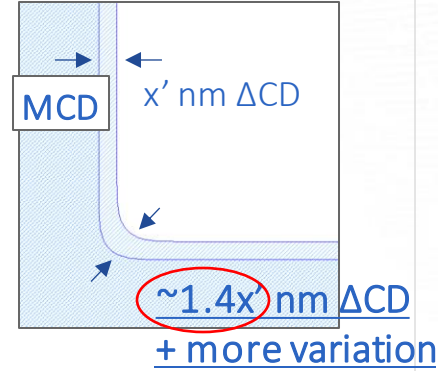
*Dose margin is bad on 90° corners*

Rectilinear

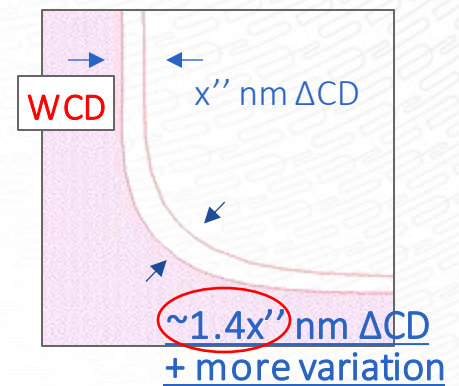
Mask Design



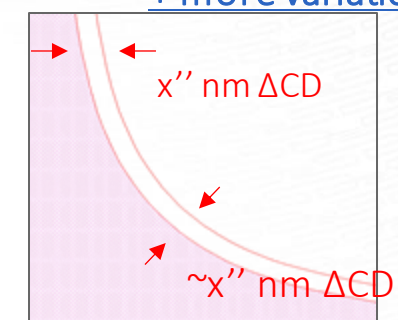
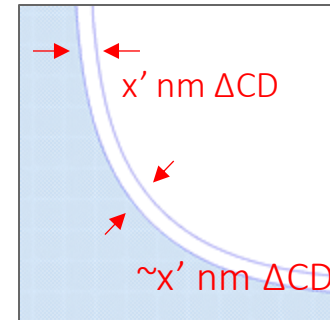
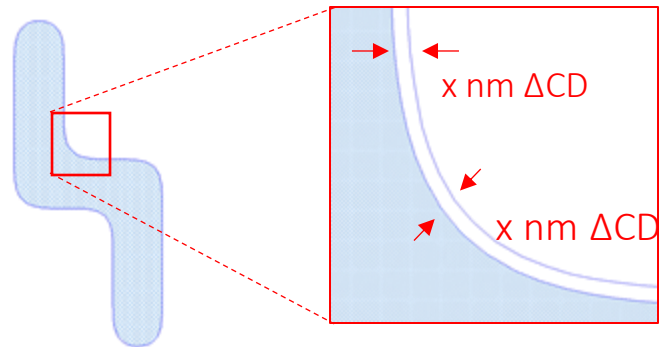
eBeam w/ bias



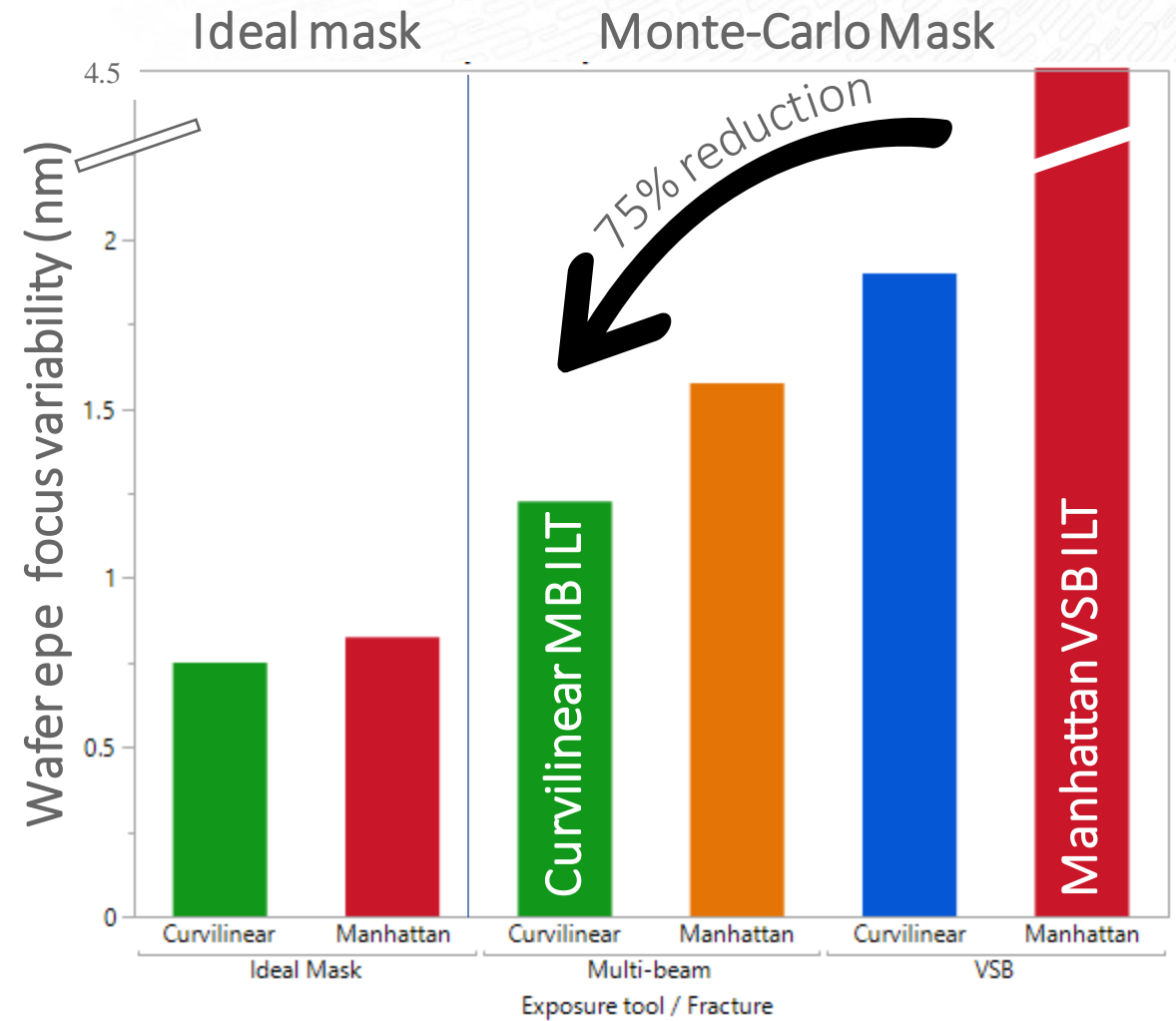
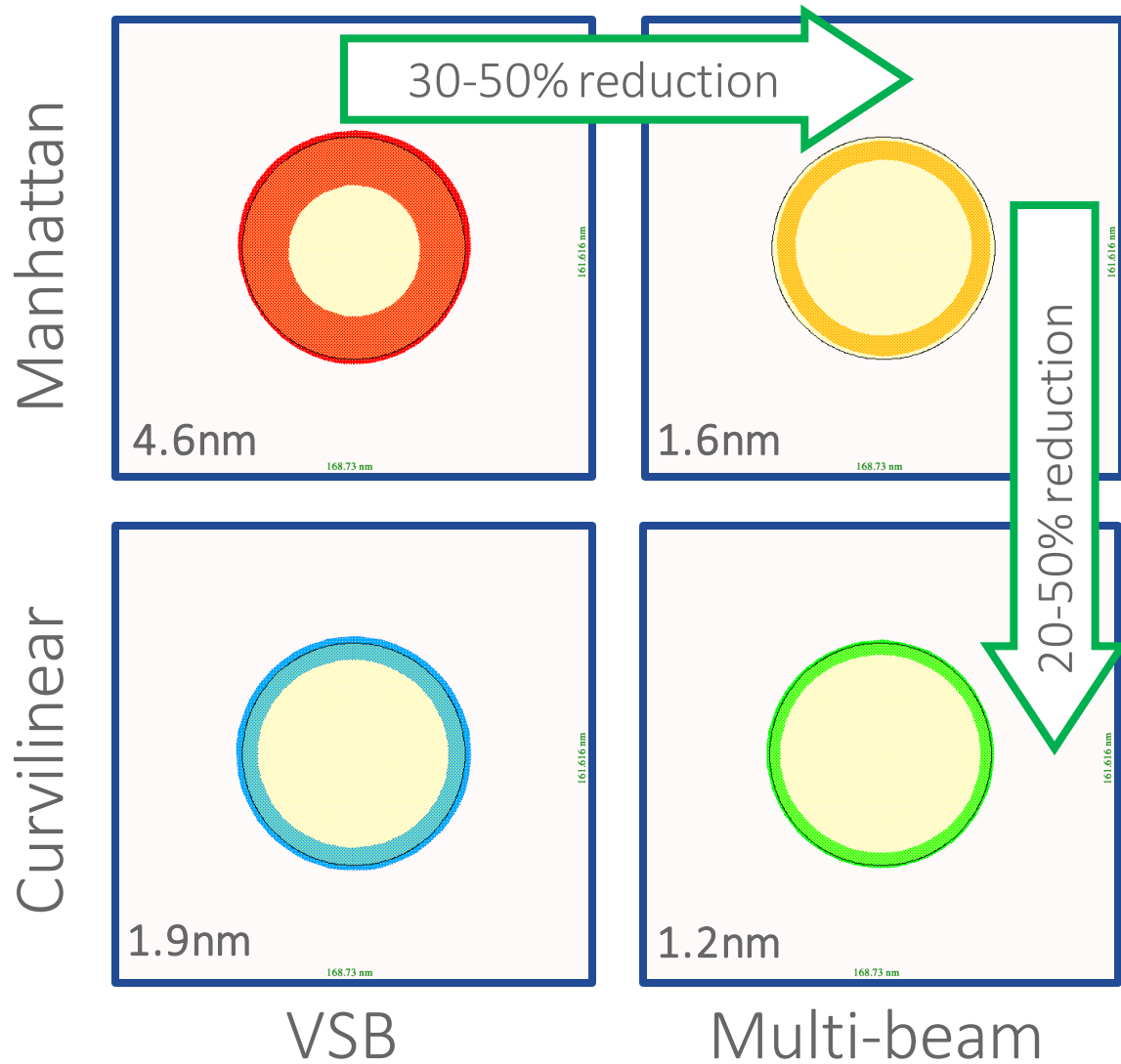
Litho sim. w/ bias



Curvilinear



# Manufacturable Shapes are More Reliably Manufacturable



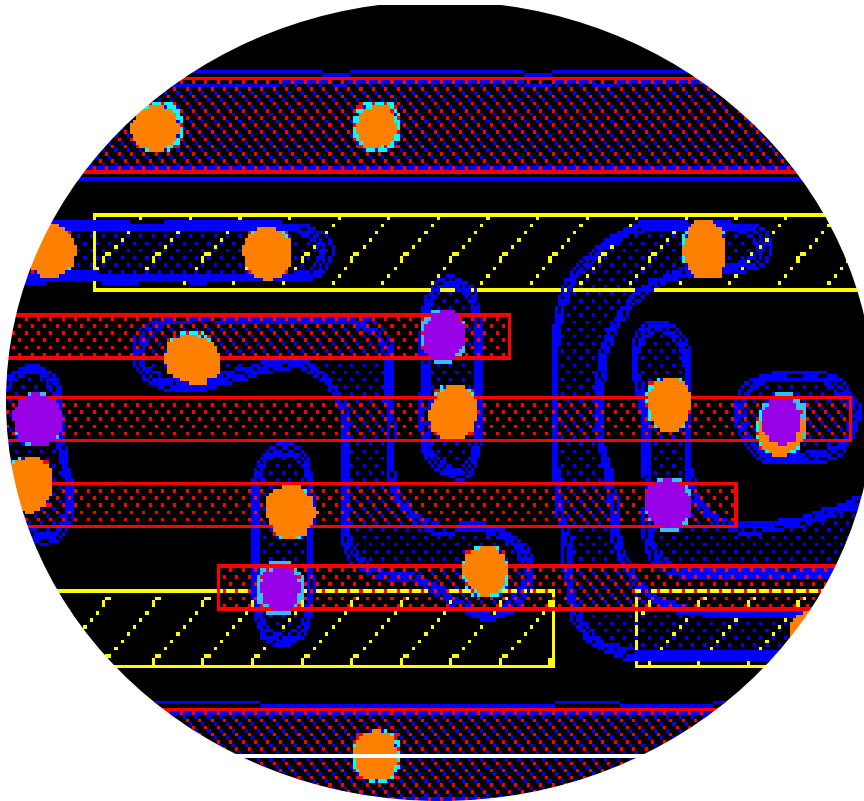
Ryan Pearman, Jeff Ungar, Nagesh Shirali, Abhishek Shendre, Mariusz Niewczas, Leo Pang, and Aki Fujimura "How curvilinear mask patterning will enhance the EUV process window: a study using rigorous wafer+mask dual simulation", Proc. SPIE 11178, (2019)



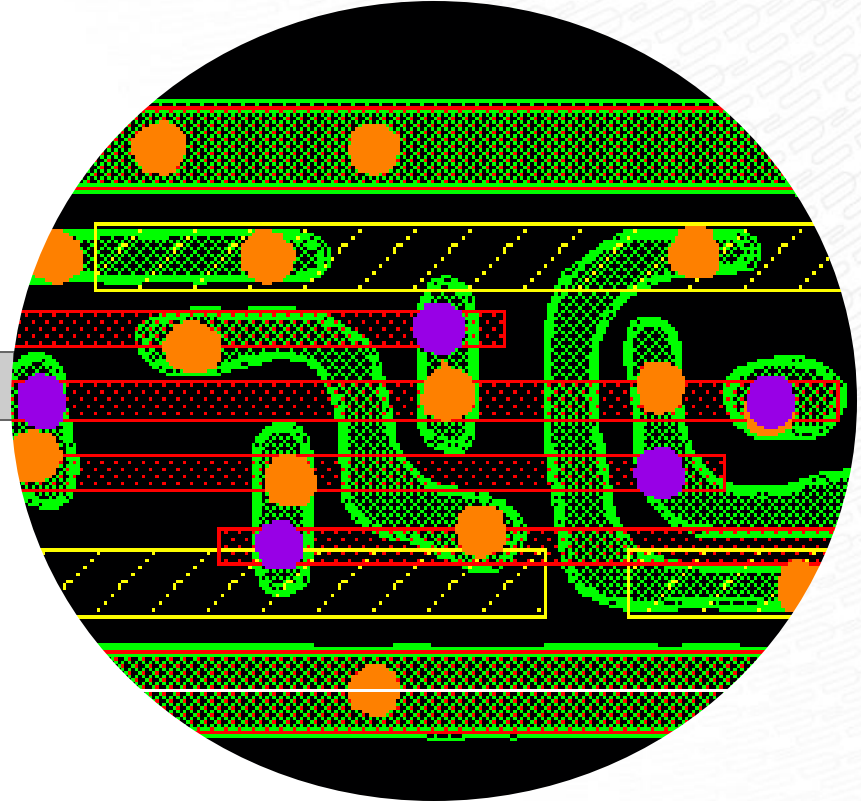
# Manufacturable Shapes are More Reliably Manufacturable

*On Wafer, too*

Design



Manufacturing



**First thing ILT does is to compute manufacturable curvy targets anyway**

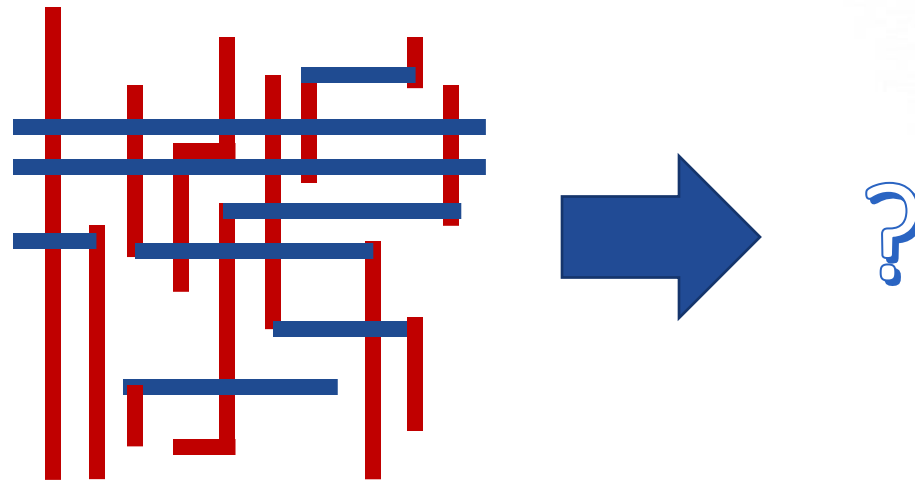


# I Presented This at Design Automation Conference

*“I was in EDA physical design since 1979 so I know it’s important for you to know:  
Curvilinear Designs are Now Manufacturable.  
In fact, More Reliably Manufacturable.”*



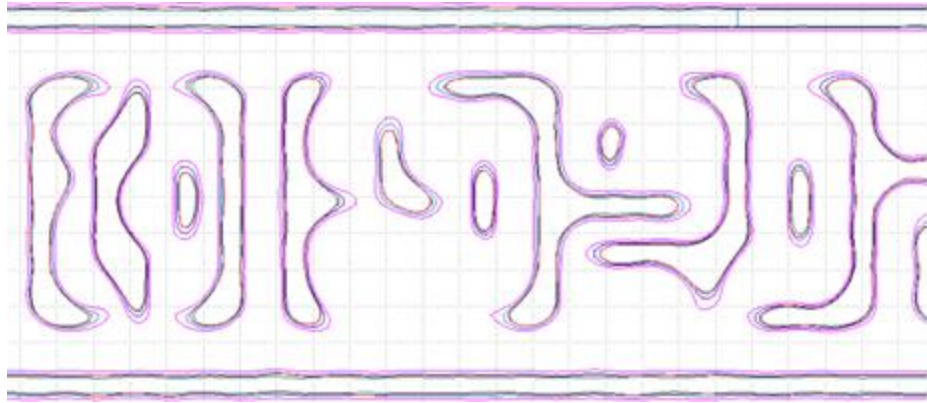
# Is it Time to Break the Manhattan Assumption?



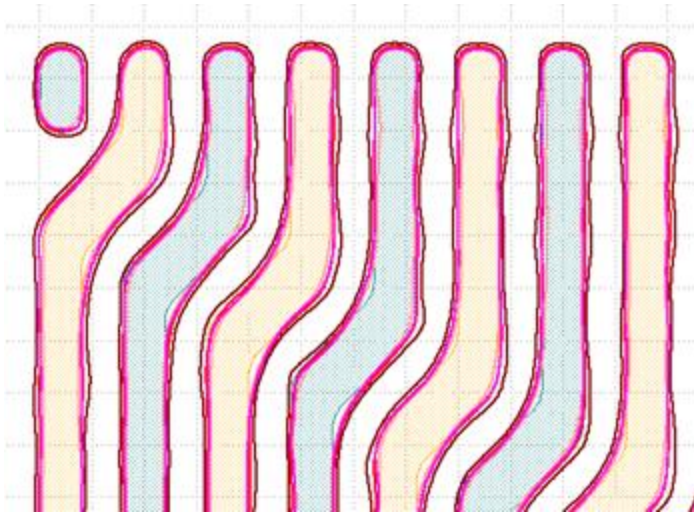
**Most chips are interconnect-limited; Reducing vias will reduce routing congestion**



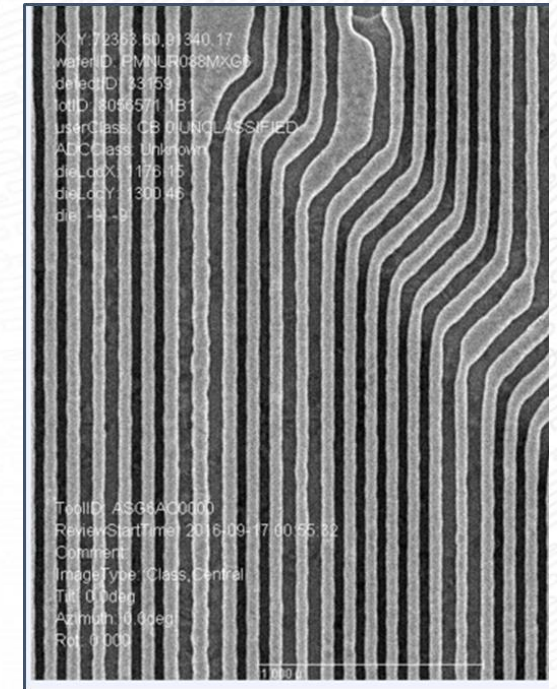
# Curvy Designs are Better for Designers, Too



- Manufacturable Curvy Designs
- Improves, all at the same time
  - Yield
  - Power
  - Performance
  - Area



- The barriers are:
  - VSB mask writing
  - EDA infrastructure

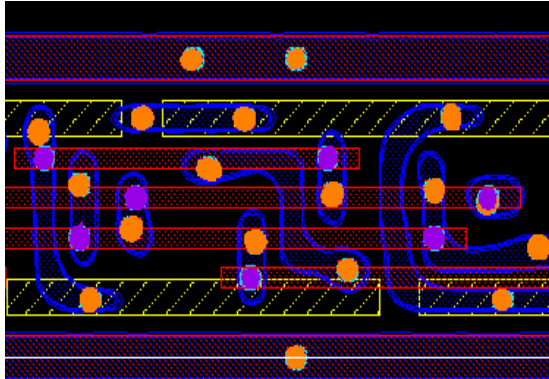


Micron

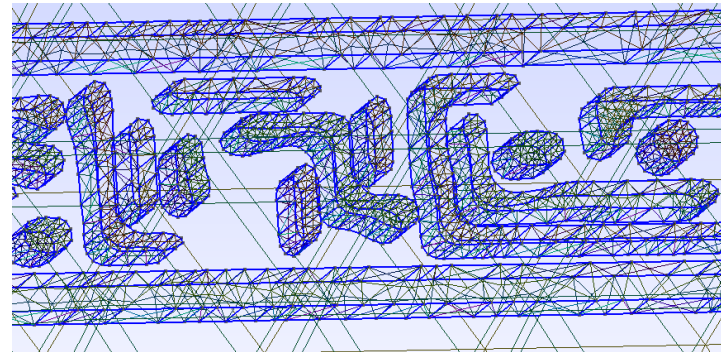
# General Perception: “Everything has to Change”

*Actually: Only Routing plus Performance Improvements*

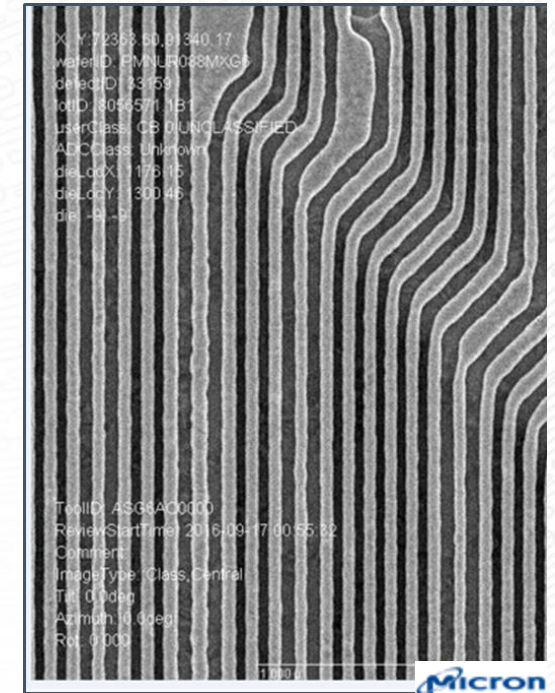
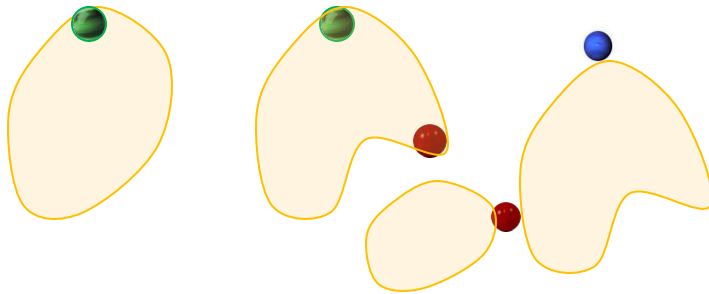
Custom Design



Parasitic Extraction

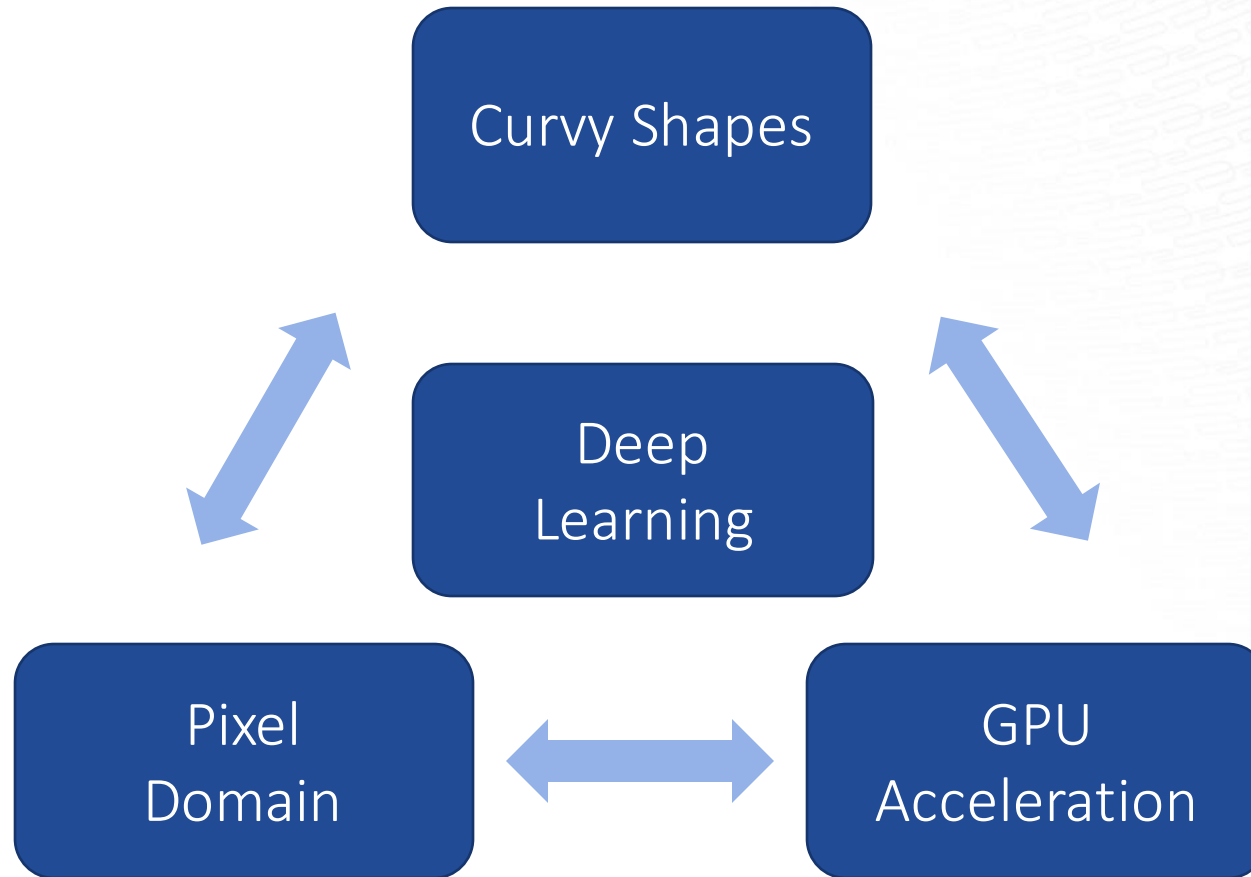


DRC/LVS



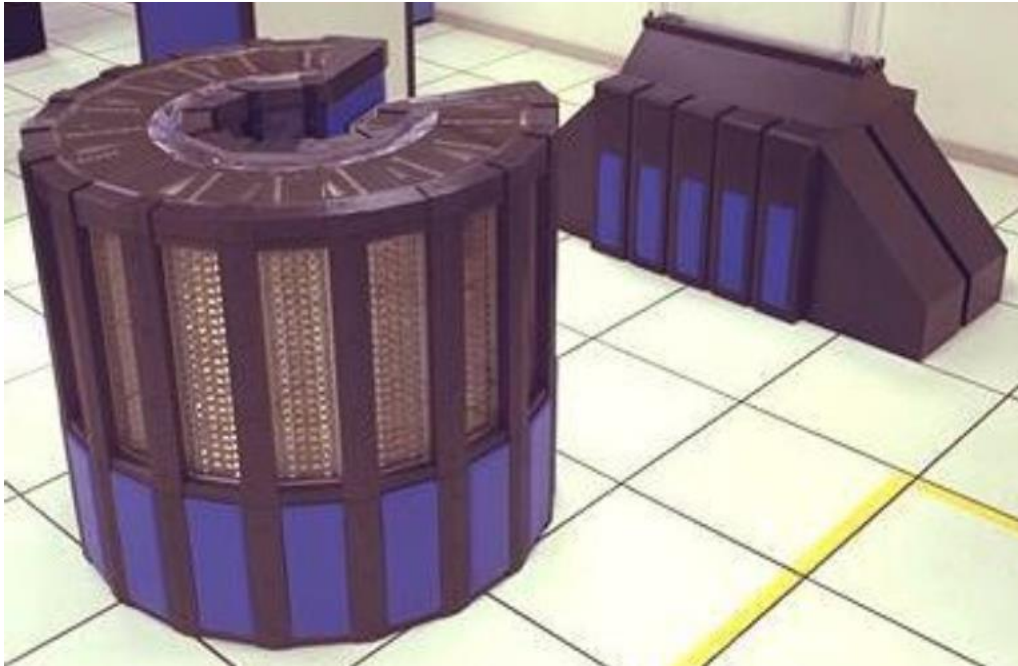
Routing

# Curvy-Pixel-GPU Can Work for Them, Too



# Today's GPU Workstation = 8,000 Cray-2s

60,000,000x Price Performance  
*It's time to rethink EDA*



Cray-2 (1985)  
1.9 GFLOPS w/500MB @ \$15M

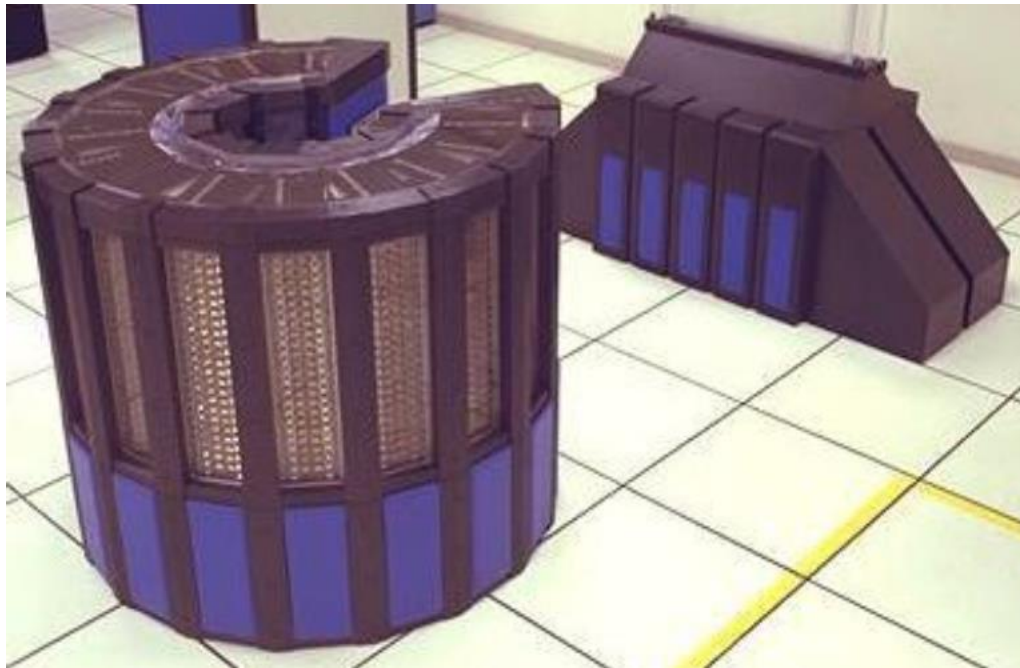


nVIDIA RTX 3090 Ti (2021)  
15,300 GFLOPS w/24GB @ \$2,000

# 16,000? Today's GPU Workstation = ~~8,000~~ Cray-2s

150,000,000x? ~~60,000,000x~~ Price Performance

*It's definitely time to rethink EDA*



Cray-2 (1985)  
1.9 GFLOPS w/500MB @ \$15M



Announced Last Tuesday





Das